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## ABSTRACT

An improved IC manufacturing process was developed to achieve the desired parameters and to obtain a transistor cut-off frequency of 10 GHz.

A typical microwave prescaler consists of a master-slave flip-flop circuit (2). To raise the prescaler toggle frequency, not only improvements in the IC manufacturing process but also circuit parameter optimization is highly desirable.

(A) prescaler simulation relies on transient analysis or iterative calculations, not on frequency response analysis.

- (A) To receive data more rapidly from the other flip-flop, the collector-to-substrate capacitance of transistor Q6, Q7 or the collector load resistance R11 must be reduced. The slope indicated by the arrow in Fig. 4 increases as these are reduced.
- (B) Additional capacitance CB in Fig. 1 synchronizes the current switch symmetrically with the input clock, as shown in Fig. 4 (without CB) and Fig. 5 (with CB).

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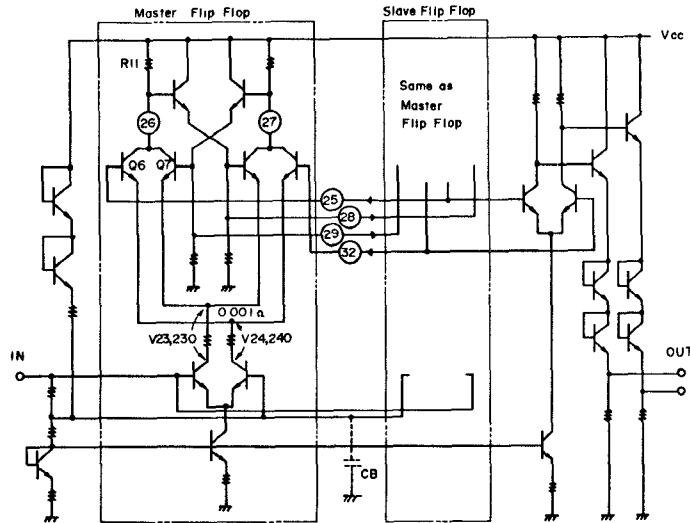


Fig. 1 Master-slave flip-flop circuit.

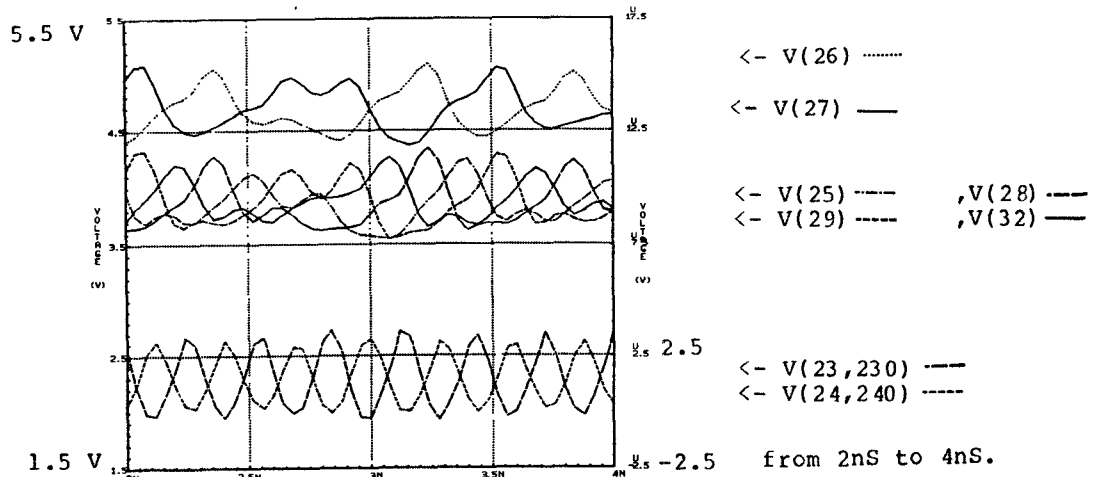


Fig.2 Simulated Waveform of Miscounting (3.4GHz).

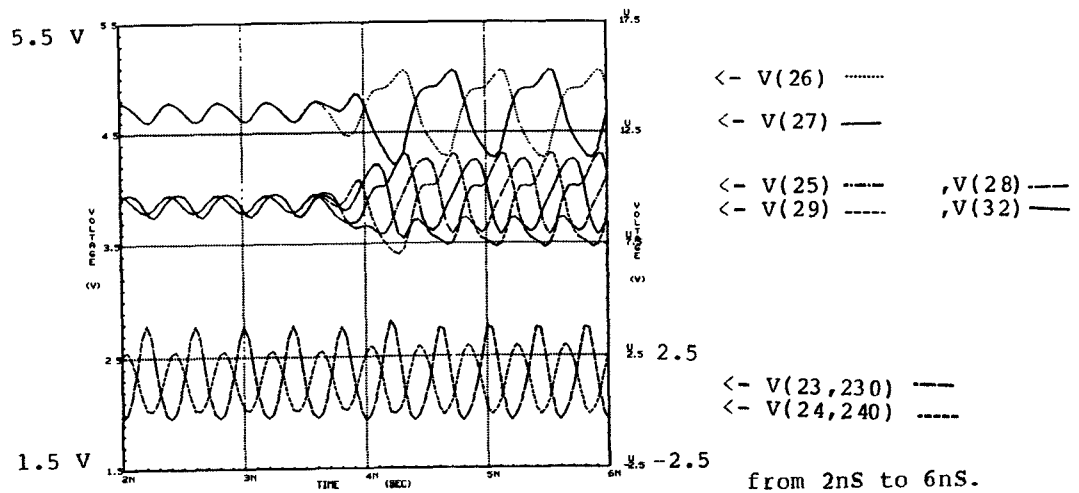


Fig.3 Start of Counting Waveform (2.5GHz).

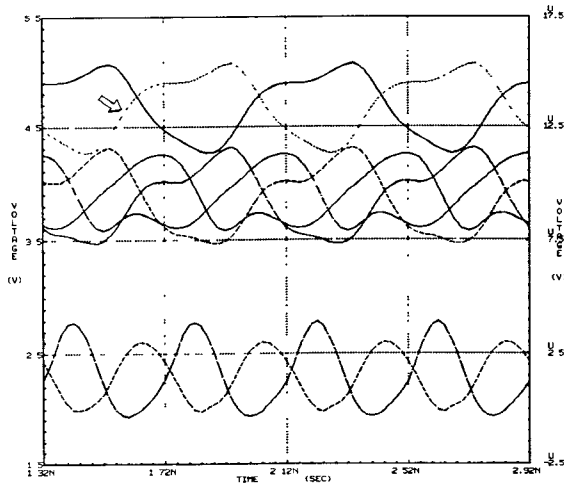


Fig.4 Precise Waveform without CB (2.5GHz).

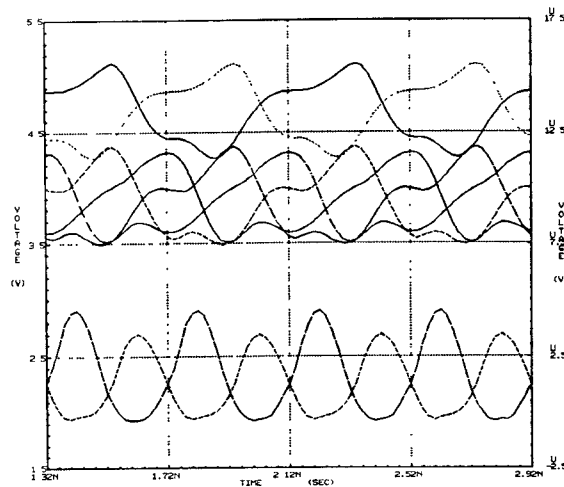


Fig.5 Precise Waveform with CB (2.5GHz).

#### PROCESS DESIGN

Several Si monolithic bipolar IC processes have been reported, most notably SST-1A (3) and APSA (4). A Si microwave monolithic IC process without self-alignment method, has also been reported (5). This process is called DNP-I (Direct Nitride Passivated base surface -I) and is capable of producing a transistor with a cut-off frequency of 6.5 GHz.

To achieve the transistor parameters determined by the computer simulation studies, the DNP-I process has been enhanced and is herein after referred to as a DNP-II process. This enhanced process has the following features:

- To reduce parasitic capacitance, oxide isolation is applied, and a smaller buried layer is selected.
- To achieve  $f_t = 10$  GHz, a shallow base ( $X_{jc} = 0.2 \mu m$ ) is formed by ion implantation and lamp-annealing. A shallow emitter ( $X_{je} = 0.1 \mu m$ ) is formed by diffusion from As-doped polysilicon.
- To reduce base resistance and E-B junction capacitance, an emitter of  $1 \mu m$  width is formed.
- To facilitate pattern design and form highly reliable electrodes, a Ti-Pt-Au electrode structure is employed.
- To achieve an extremely high reliability, the base surface is covered by an additional nitride film after the thin oxide film is applied.

A cross sectional view of a DNP-II transistor cell is shown in Fig. 6. Table 1 compares the profiles produced by DNP-I and DNP-II processes. In the case of the DNP-II profile a great contraction in pattern rule was obtained and the base and collector regions are reduced to less than 60 %. Table 2 compares the performance of transistors produced by DNP-I and DNP-II processes.

#### RESULTS

A die photograph is shown in Fig. 7 which includes the tandem two-stage master slave flip-flop from Fig.1. Additional capacitor CB is composed of a buried layer and electrode; resistors are P+ polysilicon.

Operating waveforms at 3.3 GHz are shown in Fig. 8. The maximum operating frequency of 3.9 GHz has been achieved at a power dissipation of 316 mW and a supply voltage of 5 V.

#### CONCLUSION

A prescaler IC operating up to 3.9 GHz has been developed. This IC will be useful for the size reduction of microwave local oscillators.

This new IC process, based on the latest discrete microwave transistor process, is applicable to other microwave monolithic ICs.

#### ACKNOWLEDGMENTS

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Table 1. Basic Transistor Profile Comparison.

item	DNP-I	DNP-II
Emitter width	1 $\mu$ m	1 $\mu$ m
Emitter length	40x 4 $\mu$ m	40X 4 $\mu$ m
Base area	290 4 $\mu$ m**2	15 96 $\mu$ m**2
Collector area	496 8 $\mu$ m**2	2 880 $\mu$ m**2
Electrode width	5 $\mu$ m	2 $\mu$ m
Electrode interval	2.5 $\mu$ m	2 $\mu$ m
Epitaxial thickness	1.5 $\mu$ m	1.5 $\mu$ m

Table 2. Transistor Performance Comparison.

Parameter	DNP-I	DNP-II
BVcho	25V	25V
BVceo	12V	12V
BVebo	4V	3V
hFE	100	100
fT	6.5GHz	10GHz

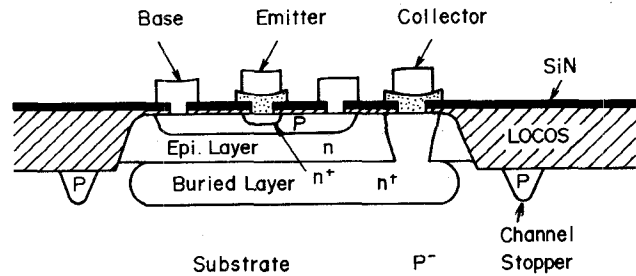


Fig. 6 A cross sectional view of transistor cell.

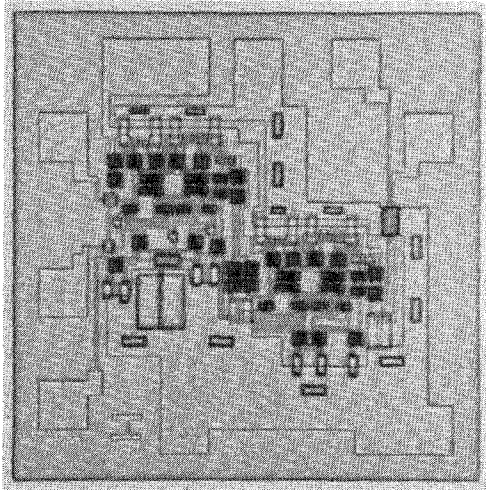


Fig.7 Die Photograph.

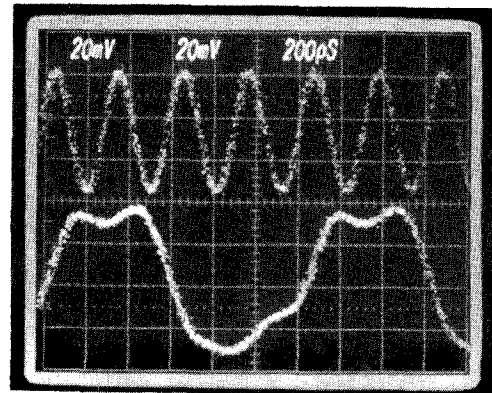


Fig. 8 Measured input output waveforms of an 1/4 divider for a 3.3 GHz sinusoidal clock.

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